

IN THE CLAIMS:

Please amend the claims as follows.

1. (Currently Amended) A capacitance type sensor comprising:

 a detective member[[,]] configured to detect an external force applied thereto;

 a first electrode ~~being opposite to facing~~ the detective member[[,]]; and

 a second electrode ~~arranged-disposed~~ between the detective member and the first
 electrode such that and constituting a capacitance element[[s]] is formed by
 ~~with the first electrode and the second electrode~~, the second electrode being
 displaceable in a ~~same~~ direction as of displacement of the detective member
 when the detective member is displaced,

 wherein a specified space is defined between the detective member and the second
 electrode, whereby the second electrode is not displaced until the detective
 member is displaced to an extent corresponding to the specified space, and

 wherein the capacitance type sensor ~~is capable of recognizing~~ identifies the
 displacement of the detective member on the basis of a detection, using a
 signal input to the first electrode, of a change in capacitance ~~value~~ of the
 capacitance element caused by a change in distance between the first
 electrode and the second electrode.

2. (Currently Amended) The capacitance type sensor according to claim 1, which has

 at least one tapered pressing member[[s]] disposed in the specified space.

3. (Currently Amended) The capacitance type sensor according to claim 1, which

further comprises a ~~single~~first substrate on which the first electrode and the second electrode are both provided.

4. (Currently Amended) The capacitance type sensor according to claim 2, which further comprises a ~~single~~first substrate on which the first electrode and the second electrode are both provided.

5. (New) The capacitance type sensor according to claim 3, further comprising:
a second substrate mounting the first substrate thereon; and
a supporting member disposed on the second substrate and configured to support the detective member.

6. (New) The capacitance type sensor according to claim 4, further comprising:
a second substrate mounting the first substrate thereon; and
a supporting member disposed on the second substrate and configured to support the detective member.

7. (New) The capacitance type sensor according to claim 3, wherein another specified space is defined between the second electrode and the second supporting member.

8. (New) The capacitance type sensor according to claim 4, wherein another specified space is defined between the second electrode and the second supporting

member.

9. (New) The capacitance type sensor according to claim 3, wherein the first substrate is a flat, plate-like member.

10. (New) The capacitance type sensor according to claim 4, wherein the first substrate is a flat-plate-like member.

11. (New) The capacitance type sensor according to claim 3, further comprising:
a third electrode disposed on the first substrate;
a reference electrode disposed on the first substrate and having a predetermined electrical potential; and
a fourth electrode electrically connecting the reference electrode and configured in a spaced relation to the third electrode, wherein the fourth electrode contacts with the third electrode by elastic deformation thereof based on the displacement of the detective member.

12. (New) The capacitance type sensor according to claim 11, wherein the detective member comprises separate members corresponding to the second electrode and the fourth electrode, respectively.

13. (New) The capacitance type sensor according to claim 4, further comprising:
a third electrode disposed on the first substrate;

a reference electrode disposed on the first substrate and grounded at a predetermined electrical potential; and
a fourth electrode electrically connecting the reference electrode and configured in a spaced relation to the third electrode, wherein the fourth electrode contacts with the third electrode by elastic deformation thereof based on the displacement of the detective member.

14. (New) The capacitance type sensor according to claim 13, wherein the detective member comprises separate members corresponding to the second electrode and the fourth electrode respectively.

15. (New) A capacitance type sensor comprising:
a substrate;
a first electrode disposed on the substrate;
a second electrode facing and spaced from the first electrode such that the first electrode and the second electrode serve as a capacitor;
a supporting member disposed on the substrate; and
a detective member configured to be supported by the supporting member and displaceable by an external force, wherein displacement of the detective member causes the second electrode to be displaced, and
wherein a specified space is defined between the detective member and the second electrode such that the displacement of the detective member is offset by the specified space.